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Forming gallium nitride-based nitride layer

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Patent Family

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Patent Details

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Abstract:

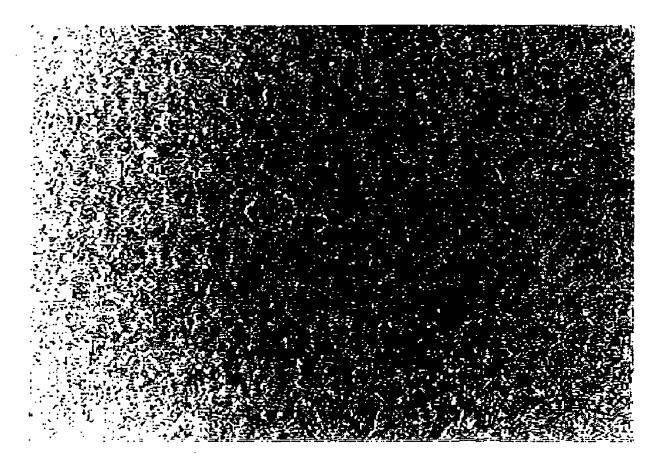
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NOVELTY A method for forming GaN-based nitride layer is provided to improve cohesion of a SiC buffer layer and a GaN-based nitride layer by forming a wetting layer on the SiC buffer layer, and to form a high-quality GaN layer by optimizing the formation of the SiC buffer layer and the wetting layer.

DETAILED DESCRIPTION A silicon carbide buffer layer is formed on a sapphire substrate. A wetting layer is formed on the silicon carbide buffer layer, having a composition of Al (x1)Ga(y1)In(z1)N(0at mostx1at most1, 0at mosty1less than1, 0at mostz1at most1, x1+y1+z1=1). A nitride layer including a GaN component is formed on the wetting layer.

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